

- L22: (18) 9 with 21
- L23: (11) 22 and 12
- L24: (779) 9 with 12
- L25: (166702) 9 near 6 18
- L26: (414) 24 and 25
- L27: (1152) 24 same 25
- L28: (2127) 27 and 21
- L29: (25) 27 and 10
- L30: (3156123) Right laser
- L31: (2026341) 9 with 20
- L32: (857233) alignment registration I
- L33: (970234) pitch grating spacing
- L34: (360508) pitch
- L35: (5782) 9 with 32
- L36: (23369) 31 with 32
- L37: (921) 36 with 34
- L38: (261) 37 and 12
- L39: (5458) smaller adj 9
- L40: (2) 12 with 39
- L41: (1891) 12 and 39
- L43: (1881) 12 and 39
- L44: (15) 12 same 39
- L42: (122) 41 and 25
- L45: (243) 16 (larger longer) adj 9
- L46: (2181) (shorter) adj 9
- L47: (4) 12 with 48
- L49: (20) 12 with 49

12 with 45

03/31/2005

	U	S	Inventor	Document	Issue P.	Title	Current	Current	I	Restrict	S	C	P	W	Image	DoP
1	<input type="checkbox"/>	<input type="checkbox"/>	Ota, Kazuya	US 5477309	1995-10	Alignment apparatus	855/67	855/53;		P	P	P	P	P	US 5477309	
2	<input type="checkbox"/>	<input type="checkbox"/>	Migita, S	US 200200	2002-10	Photomask and manufacturing metho	430/5	430/270.1		P	P	P	P	P	US 200200	
3	<input type="checkbox"/>	<input type="checkbox"/>	Okamoto, Y	US 200200	2002-41	Method of manufacturing photomask	438/37	257/12157		P	P	P	P	P	US 200200	
4	<input type="checkbox"/>	<input type="checkbox"/>	Hickman, C	US 6844883	2005-8	System for processing semiconductor	856/99			P	P	P	P	P	US 6844883	
5	<input type="checkbox"/>	<input type="checkbox"/>	Migita, S	US 6790364	2004-14	Photomask and manufacturing metho	430/5	430/322		P	P	P	P	P	US 6790364	
6	<input type="checkbox"/>	<input type="checkbox"/>	Okamoto, Y	US 6432790	2002-9	Method of manufacturing photomask	438/37	257/12157		P	P	P	P	P	US 6432790	
7	<input type="checkbox"/>	<input type="checkbox"/>	Oshino, Tets	US 6209707	2001-11	X-ray projection exposure apparatus	378/34	378/84		P	P	P	P	P	US 6209707	
8	<input type="checkbox"/>	<input type="checkbox"/>	Dirksen, Pe	US 5917604	1999-2	Alignment device and lithographic app	358/40	257/123.17		P	P	P	P	P	US 5917604	
9	<input type="checkbox"/>	<input type="checkbox"/>	Komoriya, S	US 549260	1995-5	Method of making semiconductor Inte	856/40			P	P	P	P	P	US 549260	
10	<input type="checkbox"/>	<input type="checkbox"/>	Saitoh, Ken	US 5327221	1994-13	Device for detecting positional relatio	856/50			P	P	P	P	P	US 5327221	

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